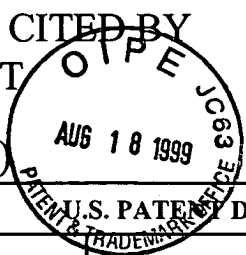


**EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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<b>LIST OF PRIOR ART CITED BY APPLICANT</b> (PTO-1449)				ATTY. DOCKET NO. <b>RPL-006</b>		APPLN. SERIAL NO. <b>09/247,866</b>	
				APPLICANT(S) <b>Tae-Wan CHOI and Seong-Ho KANG</b>			
				FILING DATE <b>February 11, 1999</b>		GROUP <b>2875 2377</b>	



U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>[Signature]</i>	5,155,414	10/13/92	SANO	315	169.4	

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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
<i>[Signature]</i>	09-160525	06/20/97	Japan	←		Abstract	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)	

EXAMINER <i>[Signature]</i>	DATE CONSIDERED <i>April 09, 2001</i>
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